# EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|---|---|---|---|---|---|---|
| L1 | 8 | @rlad<"20001220" and simulat$3 and tri-tone and (phase-shift$3 or (phase adj shift$3)) and (opc or (optical adj proximity adj correction)) and (mask or layout) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 15:50 |
| L10 | 1 | "6503666".pn. | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 09:45 |
| L11 | 29 | 09/130996 | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 09:46 |
| L13 | 8 | @rlad<"20001220" and simulat$3 and tri-tone and (opc or (optical adj proximity adj correction)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:05 |
| L14 | 1 | "5682323".pn. | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:06 |
| L15 | 258 | @rlad<"20001220" and simulat$3 and (opc or (optical adj proximity adj correction) and ((rim with width) or (phase adj shift$3))) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:36 |
| L16 | 16 | @rlad<"20001220" and simulat$3 and (opc or (optical adj proximity adj correction)) and (rim and (phase adj shift$3)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:09 |
| L17 | 8 | @rlad<"20001220" and tri-tone and (phase with shift$3) and (layout or mask) and (opc or (optical adj proximity adj correction) and rim ) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:28 |
| L18 | 8 | 15 and (tri-tone or (tri adj tone) or tritone) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:34 |

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| L19 | 253 | @rlad<"20001220" and simulat$3 and (opc or (optical adj proximity adj correction) and ((rim with width) and (phase adj shift$3))) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:36 |
| L20 | 10 | @rlad<"20001220" and simulat$3 and tri-tone | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 15:27 |
| L21 | 19 | @rlad<"20001220" and simulat$3 and (tri-tone or (tri adj tone) or tritone) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:54 |
| L22 | 12 | @rlad<"20001220" and simulat$3 and (tri-tone or (tri adj tone) or tritone) and (mask or layout) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 13:54 |
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| L24 | 0 | @rlad<"20001220" and simulat$3 and tri-tone and (opc or (optical adj proximity adj correction)) and (mask or layout) and rim | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 15:51 |
| L25 | 38 | @rlad<"20001220" and simulat$3 and (attenuat$3 with phase-shift$3 with mask) and (opc or (optical adj proximity adj correction) and (rim with width)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 16:05 |
| L26 | 18 | L25 and segment | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 16:05 |
| L27 | 7 | L26 and ((reduc$3 or downsiz$3) with (region or area)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 16:05 |
| S1 | 2 | 10/413052 | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 14:28 |

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| S2 | 1 | 10/658933 | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 14:29 |
| S3 | 3 | 09/746369 | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 15:14 |
| S4 | 1722 | @rlad<"20001220" and (opc or (optical adj proximity adj correction) and (rim with width)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 15:17 |
| S5 | 253 | @rlad<"20001220" and simulat$3 and (opc or (optical adj proximity adj correction) and (rim with width)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/24 13:07 |
| S6 | 107 | S5 and segment | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 16:34 |
| S7 | 38 | S6 and ((reduc$3 or downsiz$3) with (region or area)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 16:35 |
| S8 | 4 | S6 and ((enlarg$3 or upsiz$3) with (region or area)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 16:35 |
| S9 | 3 | @rlad<"20001220" and simulat$3 and tri-tone and (phase-shift$3 with mask) and (opc or (optical adj proximity adj correction) and (rim with width)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/24 13:26 |
| S10 | 2 | S9 and segment | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 15:23 |
| S11 | 0 | S10 and ((enlarg$3 or upsiz$3) with (region or area)) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>IBM_TDB | OR | ON | 2006/05/23 15:23 |

| S12 | 2 | S10 and ((reduc$3 or downsiz$3) with (region or area)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 15:23 |
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| S14 | 29 | 09/130996 | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 15:25 |
| S15 | 1 | "6503666".pn. | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 16:02 |
| S16 | 8 | 09/623195 | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 16:30 |
| S17 | 3 | @rlad<"20001220" and simulat$3 and tri-tone and (phase-shift$3 with mask) and (opc or (optical adj proximity adj correction)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/24 12:49 |
| S18 | 3 | @rlad<"20001220" and simulat$3 and tri-tone and (phase-shift$3 with mask) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 16:32 |
| S19 | 10 | @rlad<"20001220" and simulat$3 and tri-tone | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 16:33 |
| S20 | 38 | @rlad<"20001220" and simulat$3 and (attenuat$3 with phase-shift$3 with mask) and (opc or (optical adj proximity adj correction) and (rim with width)) | US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB | OR | ON | 2006/05/23 16:34 |
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|---|---|---|---|---|---|---|
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1. **SPIE Proceedings Vol. 3236**
   Proceedings of SPIE are timely, high-quality proceedings of technical
   conferences on optics, imaging, and photonics. ... reduction, **optical
   proximity correction (OPC)**, and phase shift lithography techniques,
   **mask**-related ... so called **Tri-tone** PSM, we can ... of the pattern
   **layout** during the exposure ...
   www.spie.org/web/abstracts/3200/3236.html - 117k - Cached - More
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2. **Semiconductor International - Application of Chromeless
   Phase Lithography (CPL) Masks in ArF Lithography -
   2/1/2003...**
   The challenges of low-k1 lithography require unique solutions at all
   levels of the lithography process. ... techniques (RETs). **Optical
   proximity correction (OPC)** is currently ... 6, a **tri-tone** inspection
   problem will ... and **mask** build to the left. The far left image is the
   actual **layout** with ...
   reed-electronics.com/SEMICONDUCTOR/article/CA273501?
   pubdate=2/1/... - More from this site - Save

3. **Search SPIE Papers - Publications - SPIE Web**
   ... Enforcement of **Mask** Rule Compliance in Model-Based **OPC**'ed
   Layouts during ... Programmable RET **Mask Layout** Verification
   [4889-151 ... Advanced 193 **tri-tone** EAPSM (9%-18%) for 65 nm
   node ...
   www.spie.org/app/publications/index.cfm?
   fuseaction=toc&volume=4889 - 83k - Cached - More from this site -
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4. **SPIE Bookstore**
   ... **OPC** to be performed on full chip **layout** ... **mask** pattern
   complexity through the elimination of optical enhancements such as
   phase shifting and **optical proximity correction** ... thin **tri-layer** ...
   bookstore.spie.org/index.cfm?fuseaction=detailvolume&... - 197k -
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5. **EFFECTING FRONTAL RADIATION MODIFICATION
   DURING EXPOSURE, E.G., SCREENING, MASKING,
   STENCILING, ETC. - Patent Storm**
   Patent Storm provides patent search capability of the US Patent
   Office patent information. Search for inventors and their inventions or
   browse the latest patents of their inventions. ... 7026081. **Optical
   proximity correction** method utilizing phase ... topography
   compensation at **mask** design: 3D **OPC** topography anchored ... as
   inputs to **mask layout** creation. Accurate predictions ...
   patentstorm.us/class/430/396-
   EFFECTING_FRONTAL_RADIATION_MODIFICATI... - 48k - Cached
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6. **acronymes**
   Bonn Germany ) BUS Broadcast and Unknown Server ( LANE ) BUT
   Board Under Test BV Bureau Veritaas BVBS BundesVereinigung der
   BauSoftwarehäuser ( Germany ) BVIT BundesVerband
   InformationsTechnologien ( e.V. ... Package CDL Capacitance-Driven

Discrete Multi-**Tone** DMTF Desktop Management Task ... GA ) GTS
Global **Tri**-State GUI Graphical User ...
www.ginko.de/user/franz.hamberger/acronyms.txt - 209k - <u>Cached</u> -
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7. <u>Structure and method of correcting proximity effects in a</u>
   <u>tri-tone attenuated phase-shifting **mask** - Patent 6653026</u>

   ... Unfortunately, a **tri-tone** phase-shifting **mask** exhibits strong ...
   **layout** and tools in use). Steps 410-430 can be performed using any
   **optical proximity correction (OPC)** tool (current **OPC** ...
   www.freepatentsonline.com/6653026.html?highlight=4902899 - <u>More</u>
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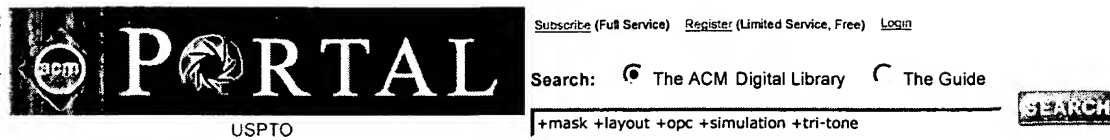
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Andrew B. Kahng, Y. C. Pati
June 1999   **Proceedings of the 36th ACM/IEEE conference on Design automation**
**Publisher:** ACM Press
Full text available: 📄 pdf(188.93 KB)   Additional Information: full citation, references, citings, index terms

**2**   Subwavelength optical lithography: challenges and impact on physical design

A. B. Kahng, Y. C. Pati
April 1999   **Proceedings of the 1999 international symposium on Physical design**
**Publisher:** ACM Press
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**3**   Fast Prolog with an extended general purpose architecture

Bruce K. Holmer, Barton Sano, Michael Carlton, Peter Van Roy, Ralph Haygood, William R. Bush, Alvin M. Despain, Joan M. Pendleton, Tep Dobry
May 1990   **ACM SIGARCH Computer Architecture News , Proceedings of the 17th annual international symposium on Computer Architecture ISCA '90**, Volume 18 Issue 3a
**Publisher:** ACM Press
Full text available: 📄 pdf(1.19 MB)   Additional Information: full citation, abstract, references, citings, index terms

Most Prolog machines have been based on specialized architectures. Our goal is to start with a general purpose architecture and determine a minimal set of extensions for high performance Prolog execution. We have developed both the architecture and optimizing compiler simultaneously, drawing on results of previous implementations. We find that most Prolog specific operations can be done satisfactorily in software; however, there is a crucial set of features that the architecture must suppor ...

**4**   Filling and slotting: analysis and algorithms

Andrew B. Kahng, Gabriel Robins, Anish Singh, Huijuan Wang, Alexander Zelikovsky
April 1998   **Proceedings of the 1998 international symposium on Physical design**
**Publisher:** ACM Press
Full text available: 📄 pdf(1.19 MB)   Additional Information: full citation, abstract, references, citings, index terms

In very deep-submicron VLSI, certain manufacturing steps &mdash notably optical exposure, resist development and etch, chemical vapor deposition and chemical-mechanical polishing (CMP)&mdash have varying effects on device and interconnect features depending on local characteristics of the layout. To make these effects uniform and predictable, the layout itself must be made uniform with respect to certain density parameters. Traditionally, only foundries have performed the p ...

5

## A methodology for modeling the effects of systematic within-die interconnect and device variation on circuit performance

Vikas Mehrotra, Shiou Lin Sam, Duane Boning, Anantha Chandrakasan, Rakesh Vallishayee, Sani Nassif

June 2000    **Proceedings of the 37th conference on Design automation**

**Publisher: ACM Press**

Full text available: pdf(1.01 MB)            Additional Information: full citation, abstract, references, citings, index terms

We present a methodology to study the impact of spatial pattern dependent variation on circuit performance and implement the technique in a CAD framework. We investigate the effects of interconnect CMP and poly CD device variation on interconnect delay and clock skew in both aluminum and copper interconnect technology. Our results indicate that interconnect CMP variation strongly affects interconnect delay, while poly CD variation has a large impact on clock skew in a 1 GHz design. Given th ...

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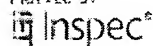**No results were found.**

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